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U.S. Department of Commerce, Patent and Trademark Office						Serial No.: Unknown				
						Filing Date: 12/20/01				
INFORMATION DISCLOSURE STATEMENT BY APPLICANT						Inventors: Novotny, et al				
''MULTI-AXIS MICRO-ELECTRO-MÉCHANICAL ACTUATOR"						Group Art Unit: Unknown				
						Examiner Name: Unknown				
Express Mail Receipt No. EF055078353US					Attorney Docket No.: AO-001					
			U.S. I	Patent Document	s					
*Examiner Initial		Document Number	Date	Name	Class		Subclass	Filing If Appropr		
w.c	AA	6,301,403 B1	10/09/01	Heanue et al.	3	85	18			
W.C-	AB	6,253,001 B1	06/26/01	Storrs T. Hoen	3	85	17		_	
۰). در	AC	6,028,689	02/22/00	Michalicek et al.	3	59	224			
ن، در	AD	5,872,880	02/16/99	Ronald S. Maynard	3	85	88			
W.(·	AE	6,283,601 B1	09/04/01	Hagelin et al.	3	59	871			
			Foreign	Patent Documen	nts					
								Transla	tion	
		Document Number	Date	Country	С	lass	Subclass	Yes	No	
	AF				+-					
OTH	ER A	RT (Includi	ng Author	, Title, Date,	Pe	rtine	ent Pages,	, Etc.)		
<i>ω</i> . <i>ω</i>	AG	RT (Including Author, Title, Date, Pertinent Pages, Etc.) "ROUTING PACKETS WITH LIGHT," Daniel J. Blumenthal. Scientific								
	АН	American, pages 96-99. January 2001. "Construction and performance of a 576x576 single-stage OXC," Herzel								
رم س-(م		Laor. LEOS, San Francisco, California, 3 pages. November 8, 1999.								
لا .ر ،	AI	"Application of micro- and nanotechnologies for the fabrication of optical devices," Wolfgang Ehrfeld and Hans-Dieter Bauer. SPIE Vol. 3276, page 2 and pages 4-14.								
	AJ	"PERFORMANCE OF A 576x576 OPTICAL CROSS CONNECT," Laor, et al. NFOEC, Chicago, Illinois, pages 1-5. September 26, 1999.								
ب، در		"Control and shape design of an electrically-damped comb drive for digital switches," Yijian Chen. Proceedings of SPIE Vol. 4178, 2000. Pages387-394.								
(w .(·	AK	''Control and digital swit	ches," Yij						00.	

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

U.S. Department of Commerce, Patent and Trademark Office						Serial No.: Unknown				
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						Examiner Name: Unknown				
Express Mail Receipt No. EF055078353US						Attorney Docket No.: AO-001				
U.S. Patent Documents										
*Examiner Initial	:	Document Number	Date	Name	Class		Subclass	Filing Date, If Appropriate		
<u> </u>	AL				ــ			7-		
Foreign Patent Documents										
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-		Document Number	Date	Country	C:	lass	Subclass	Yes	No	
	AM	Humber								
OTH	OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)									
60.4	AN	''THE RISE OF OPTICAL SWITCHING,'' David J. Bishop et al. Scientific American, pages 88-94. January 2001.								
υ (·	AO	"A LARGE-DEFLECTION ELECTROSTATIC ACTUATOR FOR OPTICAL SWITCHING APPLICATIONS," John D. Grade, Hal Jerman and Thomas W. Kenny. Presented at Hilton Head, 2000. 4 pages.								
i, C	AP	"FLIP CHIP CHALLENGES," Steve Bezuk, PH.D. General Manager, Applied Technology Development and Flip Chip Kyocera America, Inc. First published in HDI Magazine, February 2000. 6 pages.								
w.c	AQ	"MEMS Feedback Control Using Through-Wafer Optical Device Monitoring," J.M. Dawson, et al. Proceedings of SPIE Vol. 4178, 2000. Pages 221-227.								
۵.۷	AR	"A FLAT HIGH-FREQUENCY SCANNING MICROMIRROR," Robert A. Conant, et al. 2000 Solid-State Sensor & Act Workshop, Hilton Head, S.C., June 4-8, 2000.								
w.C.	AS	"The Surface/Bulk Micromachining (SBM) Process: A New Method for Fabricating Released MEMS in Single Crystal Silicon," Sangwoo Lee, et al. Journal of Microeletromechanical Systems, Vol. 8, No. 4, December 1999. Pages 409-416.								
v·c·	ΆΤ	"MEMS actuators for silicon micro-optical elements," Norman C. Tien and Daniel T. McCormick. Proceedings of SPIE Vol. 4178, 2000. 256-267.								
Examiner	6	QC_	Dā	ate Considered	8	3/22	63			

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

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U.S. Department of Commerce, Patent and Trademark Office						Serial No.: Unknown				
						Filing Date: 12/20/01				
INF	ORMAT	ION DISCLOSURE	Inver	Inventors: Novotny, et al.						
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U.S. Patent Documents										
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date, If Appropriate			
	AU									
Foreign Patent Documents										
						Translation				
		Document Number	Date	Country	Class	Subclass	Yes	No		
	AV	Number								
ОТН	ER A	RT (Includi:	ng Author	, Title, Date, 1	Pertine	nt Pages,	Etc.)			
، ک. دے	AW	''Lightweight, Optically Flat Micromirrors for Fast Beam Steering,'' Jocelyn T. Nee, et al. Presented at IEEE/LEOS Optical MEMS 2000 Conference, August 21-4, 2000, Kauai, Hawaii, USA. 2 pages.								
W-C	AX	"Optical MEMS for Optical Communications - Trends and Developments," Veljko Milanovic. Adriatic Research Institute. Pages 2-6. Downloaded December 20, 2001.								
	AY									
	AZ									
	BA									
	BB									
	вс									
Examiner		\mathcal{Q}	Da	te Considered	E/20/3	/3				
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